

FIG. 1A PRIOR ART

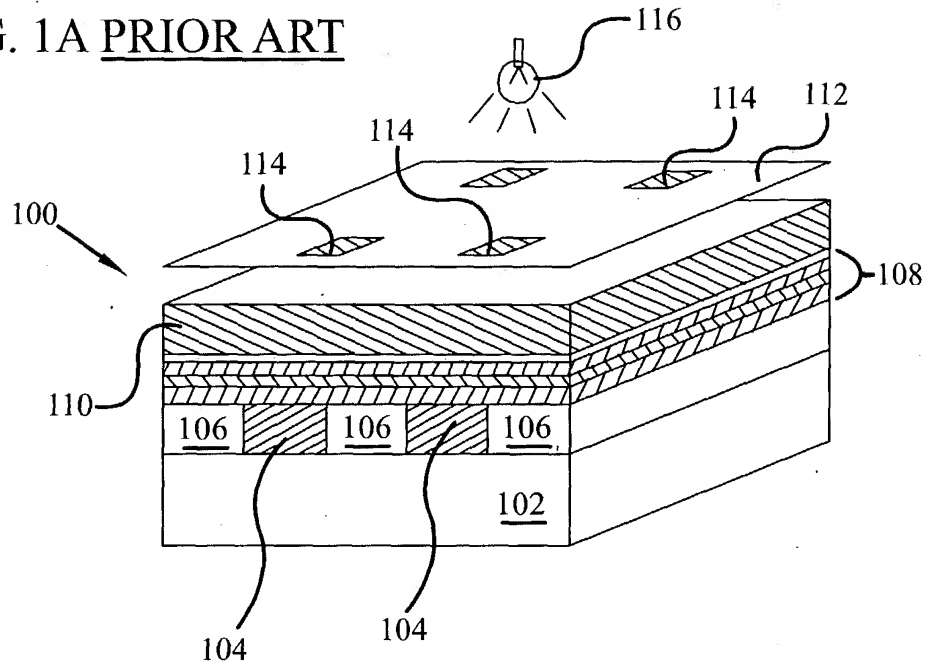
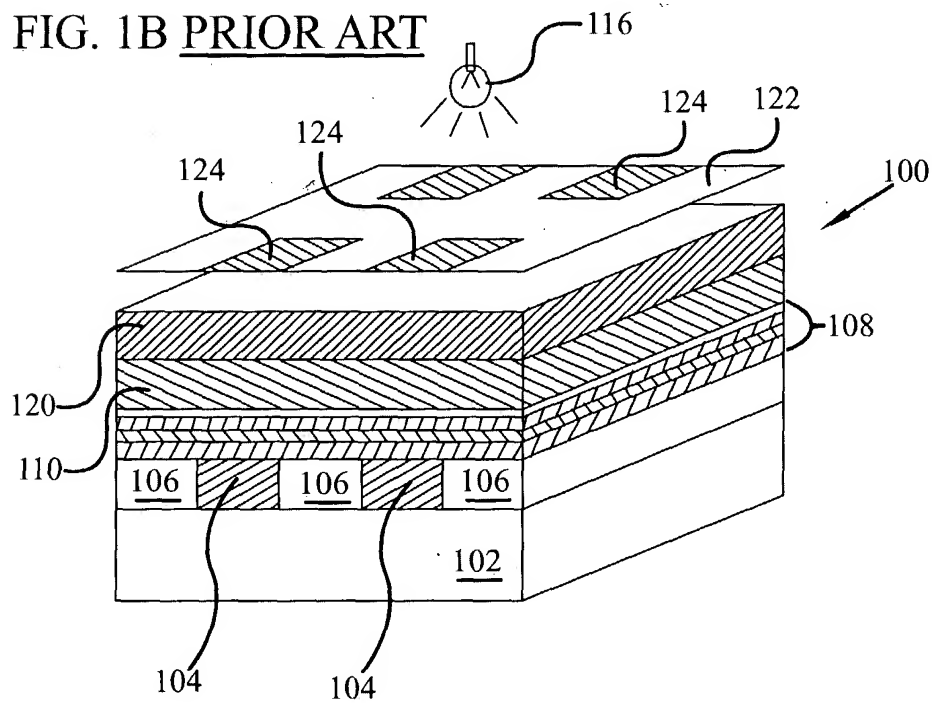


FIG. 1B PRIOR ART



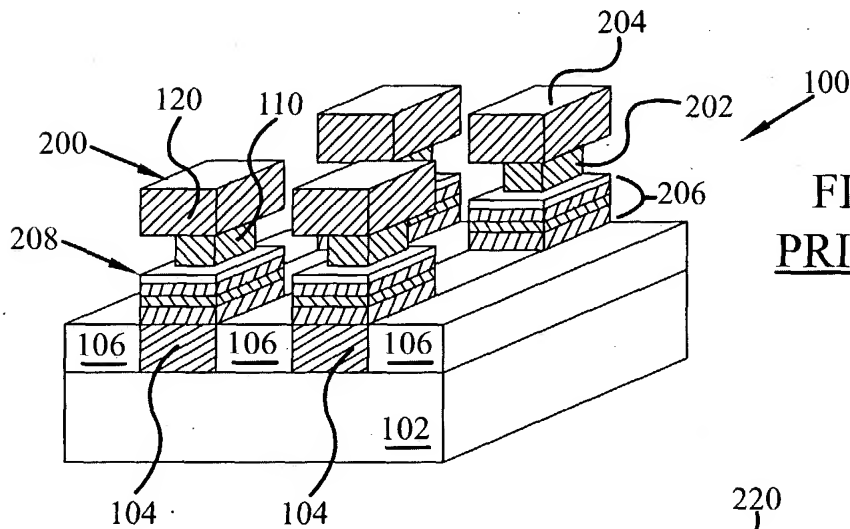


FIG. 2A  
PRIOR ART

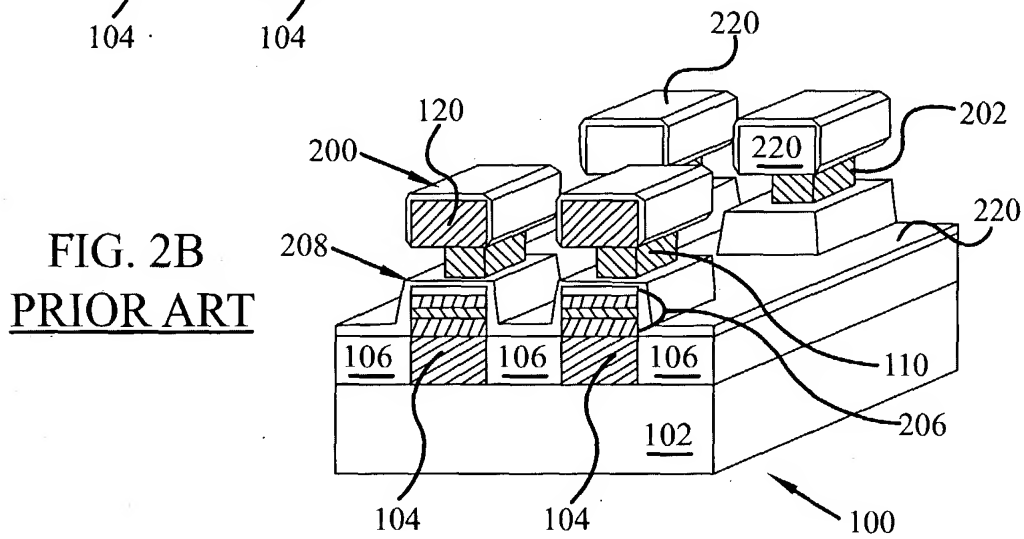


FIG. 2B  
PRIOR ART

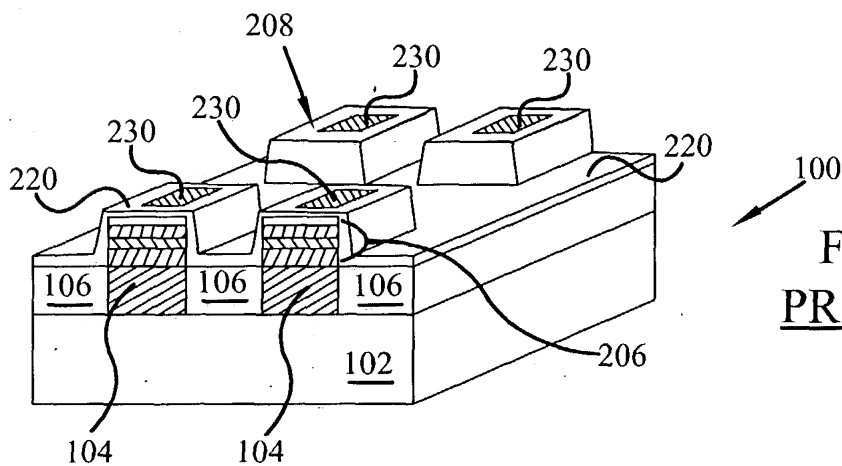
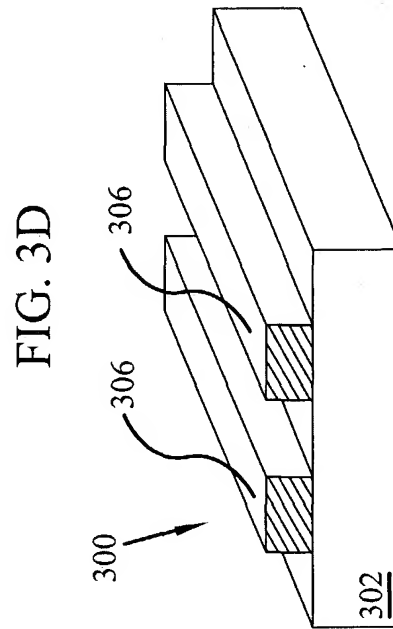
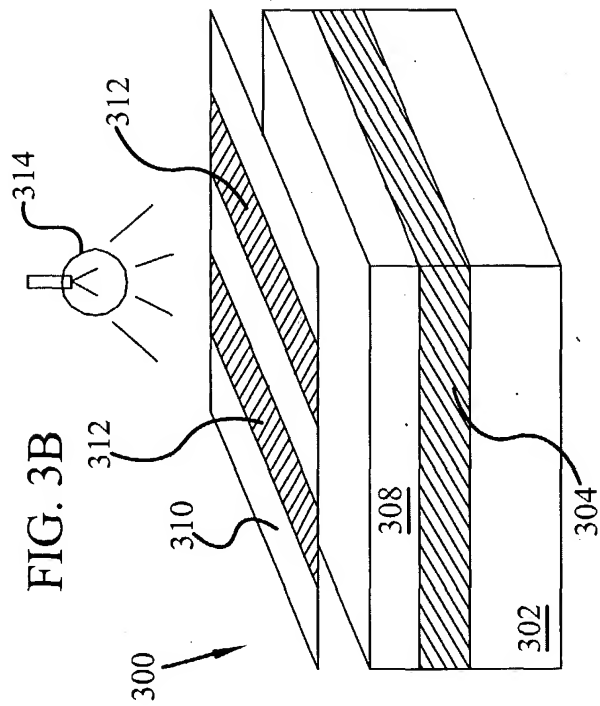
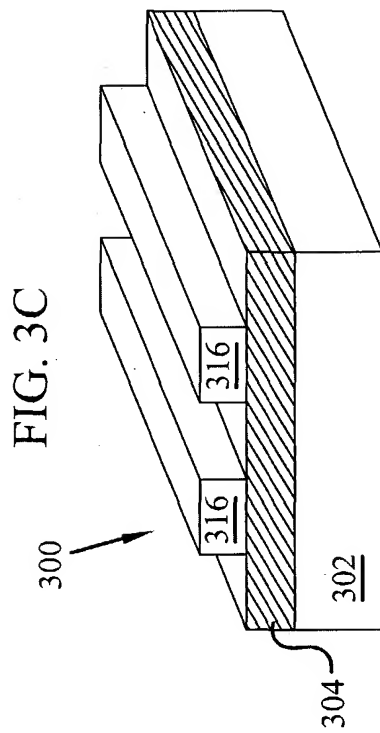
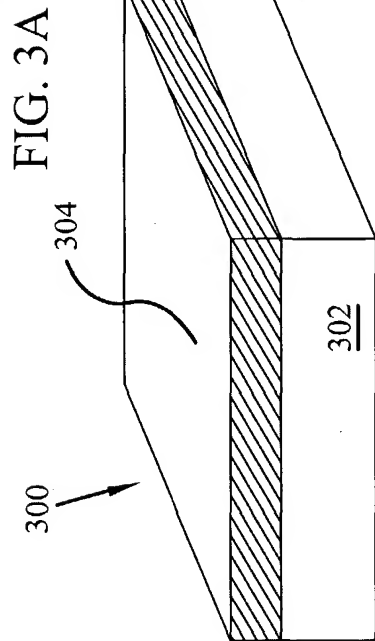
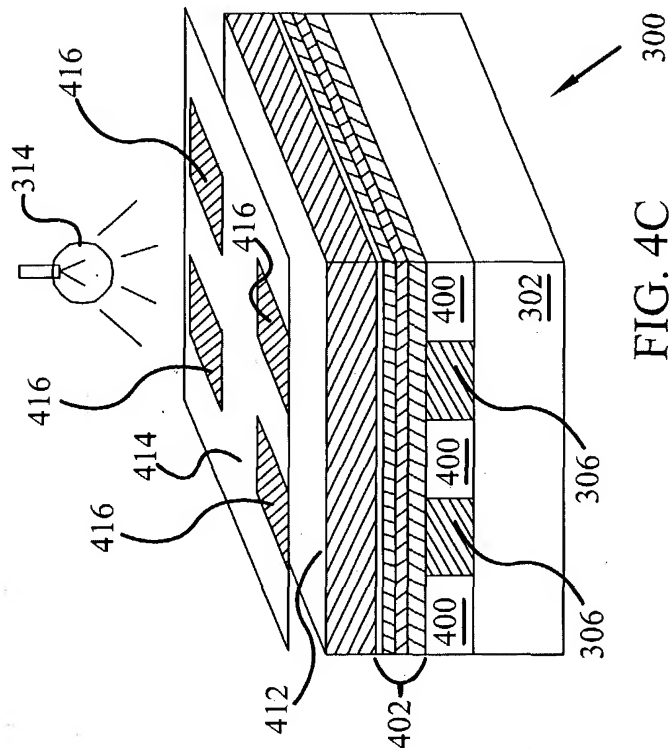
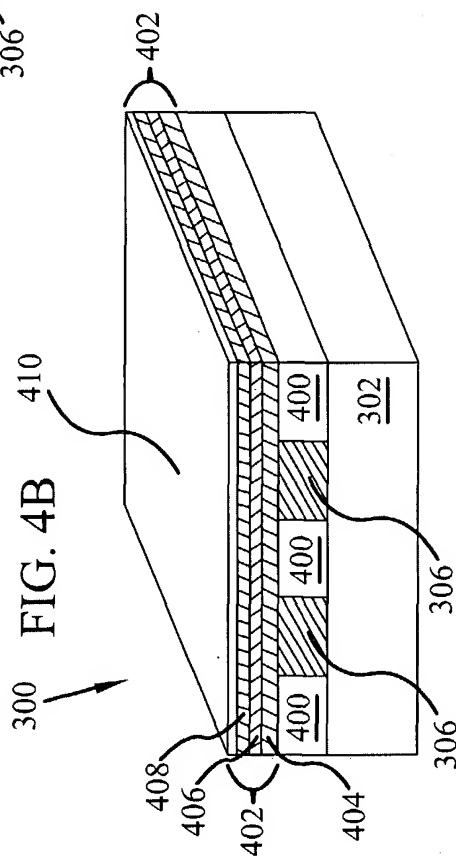
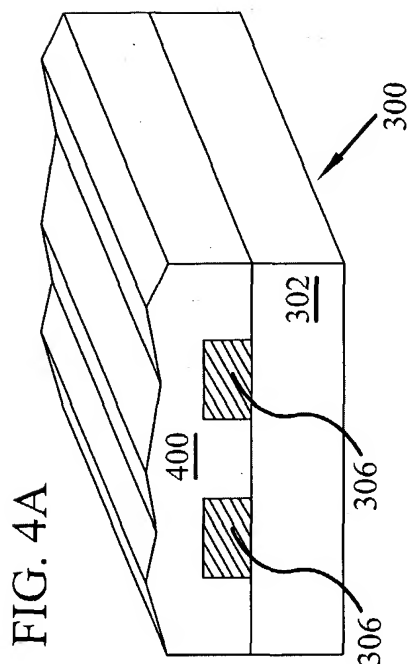
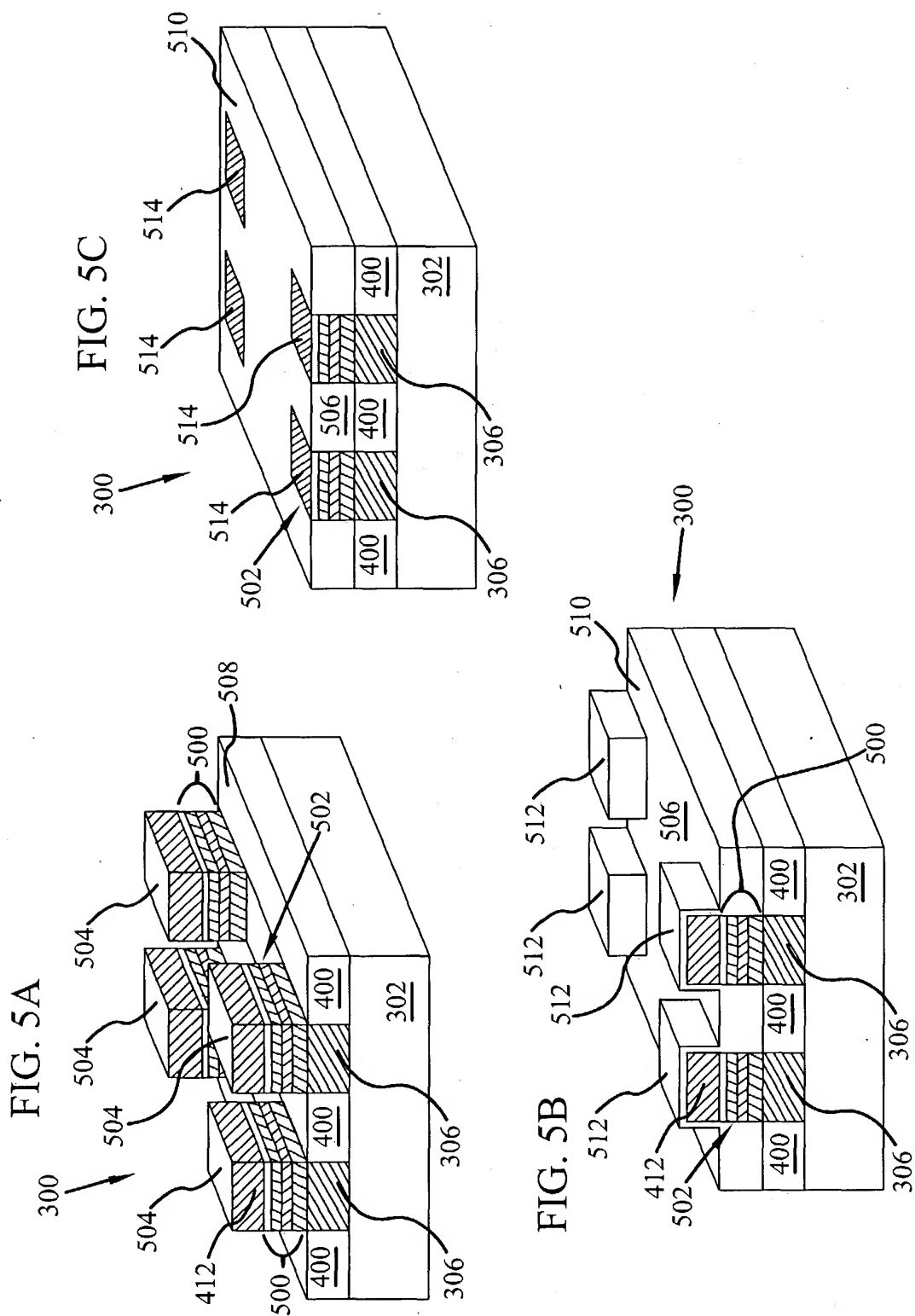


FIG. 2C  
PRIOR ART







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FIG. 6A

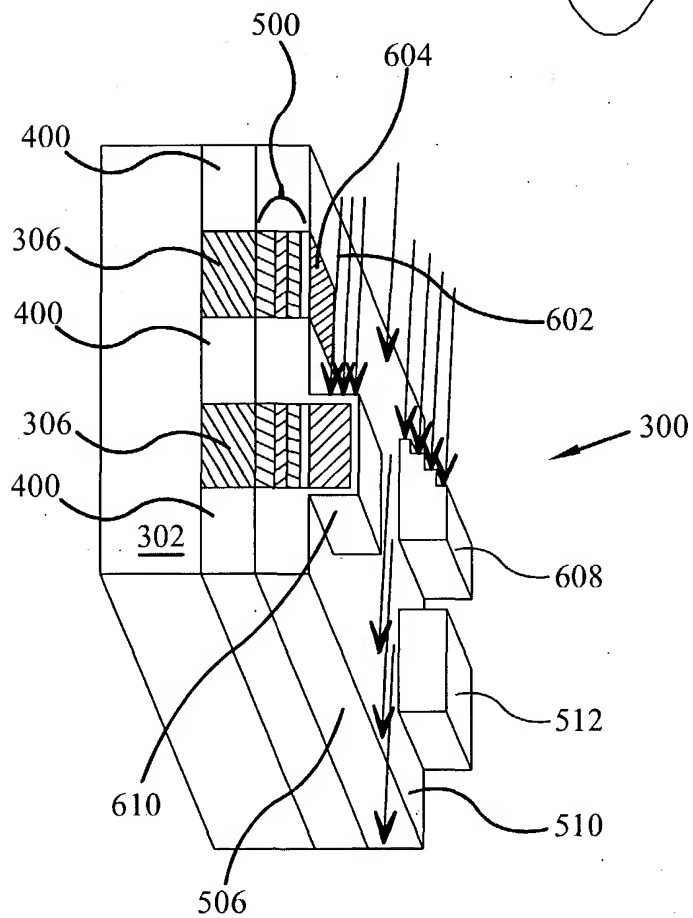
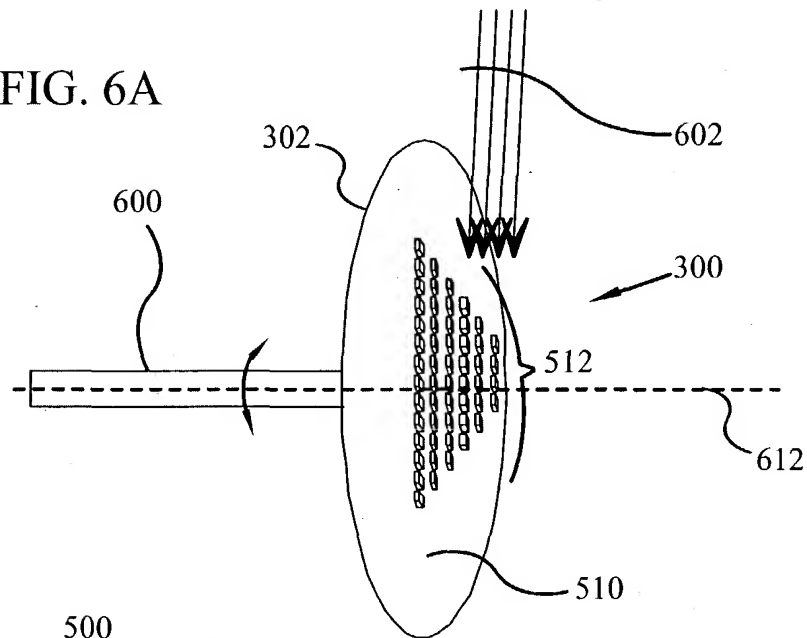


FIG. 6B

# DIRECTIONAL ION ETCHING PROCESS FOR PATTERNING SELF-ALIGNED VIA CONTACTS

Manish Sharma

HP Docket No. 200300153-1

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